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Date: 14.09.2021

Corrigendum – I

For (PR No. 1000018307) RfX No. 6100000812 – Reactive Ion Etching System
(RIE)

Sr.No.	Online RfX Clause	Previous Clause	Changed Clause
1	Bid Submission End Date/Date & Time of Submission (Online RfX Clause)	16.09.2021 at 13:00	27.09.2021 at 13:00
2	Bid Opening Date & Time (Online RfX Clause)	16.09.2021 at 16:00	27.09.2021 at 16:00

- Kindly note that technical specification has been amended. Please check below.

	Original Specs	Amended Specs
Point 2.(b).k	The main chamber must be able to reach (in half an hour) and maintain a vacuum level of less than 5×10^{-6} torr during standard etching processes.	The main chamber must be able to reach (in half an hour) and maintain a vacuum level (base pressure) of less than 5×10^{-6} torr. Process pressure should be in range 2-100 mtorr"
Point 2.(b).n	The plasma should be inductively coupled with an operating frequency of standard 13.56 MHz.	The plasma should be inductively coupled with an operating frequency of 2 MHz or 13.56 MHz.


Additional Registrar
Material Management